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U.S.S.N. 09/941,537

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Chen et al.

Group Art Unit: 1756

Serial No.: 09/941,537

Examiner: J. S. Ruggles

Filed: 08/29/2001

In Response to Office Action
Dated: 04/30/2003

For: METHOD FOR REDUCING LIGHT REFLECTANCE IN A PHOTOLITHOGRAPHIC
PROCESS

Attorney Docket No.: 67,200-477

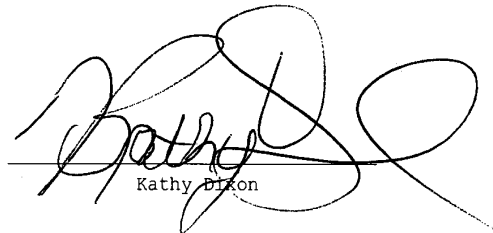
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Commissioner for Patents
P.O. Box 1450
Alexandria, Va 22313-1450

Date:

7/30/2003



Kathy Dixon

RESPONSE TO OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, Va 22313-1450

Dear Sir:

In response to an Office Action mailed 04/30/2003,
please enter the following amendments and consider the following
remarks.